

ABSTRACT**Radiation Source, Lithographic Apparatus,
and Device Manufacturing Method.**

A radiation source unit comprising an anode and a cathode that are configured and arranged to create a discharge in a substance in a space between said anode
5 and cathode and to form a plasma so as to generate electromagnetic radiation. The liquid may comprise xenon, indium, lithium, tin or any suitable material.

To improve conversion efficiency, the source unit is constructed to have a low inductance, and operated with a minimum of plasma.

To improve heat dissipation, a fluid circulation system is created within the
10 source volume and the wick by using a fluid in both its vapor and liquid states.

To prevent contamination from entering a lithographic projection apparatus, the source unit is constructed to minimize the production of contamination, and a trap is employed to capture the contamination without interfering with the emitted radiation.

15 Fig. 2A